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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Mutsumi KIMURA

Group Art Unit: 2818

Application No.: 10/765,200

Examiner: P. DANG

Filed: January 28, 2004

Docket No.: 118319

For: METHOD OF MANUFACTURING THIN FILM ELEMENT, THIN FILM TRANSISTOR
CIRCUIT SUBSTRATE, ACTIVE MATRIX DISPLAY DEVICE, ELECTRO-OPTICAL
DEVICE, AND ELECTRONIC APPARATUS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed more than three months after the U.S. filing date AND after the mailing date of the first Office Action on the merits, but before the mailing date of a Final Rejection, Notice of Allowance or other action that closes prosecution (e.g., Quayle Action).
- ☒ a. I hereby certify that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement. 37 CFR §1.97(e)(1).
- ☒ 2. References 1 and 2 were cited in a counterpart foreign application.
- ☒ 3. An English language Abstract of the non-English language reference 1 is attached hereto.

- ☒ 4. A computer-generated English language translation of the following Japanese Patent Publication has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See Reference 1.

Respectfully submitted,



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JAO:GXL/axl

Date: December 5, 2005

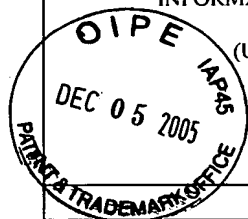
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Form PTO-1449
(REV. 8-83)US Dept. of Commerce
PATENT & TRADEMARK OFFICEATTY DOCKET NO.
118319APPLICATION NO.
10/765,200

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

APPLICANT
Mutsumi KIMURAFILING DATE
January 28, 2004GROUP
2818

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS
	1.	JP A 11-282995 w/Abstract and Translation	10/15/1999	Japan		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	2.	S. Utsunomiya et al., "Low Temperature Poly-SI TFT-LCD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA [®]), Asia Display/IDW '01, pages 339-342

EXAMINER

DATE CONSIDERED

Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: December 5, 2005